(Please fill in the form. Thank	you very much.)		
課程名稱 Course name_	(中): 奈米材料(S)TEM 電鏡分析原理與技術		
at least in English, additionally in Chinese preferred	(Eng): Nano-material characterization wit	th a (S)TEM	
授課老師所屬單位 Offering dept. and university	Laboratoire de Physique des Solides UMR8502 CNRS / Université Paris-Sud, France.		
授課教師資料 Offering teacher's information	Name: GLOTER AlexandreTel. / mobile phone number:+33682867054Email: gloter@lps.u-psud.fr		
學經歷 Curriculum vitae	Education: Solid state physic, PhD.	☐ Morning (9:00~12:00) ☑Afternoon (14:00~17:00)	
課程開辦系所 Hosting Department	Professional appointment: Senior researcher in Solid State Laboratory, CNRS University Paris Sud 11, 91405 Orsay, France.		
授課教師資料 Offering teacher's information	Other qualification:		
學分數 Credit(s) 課程目標 Goal of this course description within 150 words 跟程簡述 Course description description within 350 words	Other qualification: 1 The goal of this course is to teach to the students about the transmission electron microscopy (TEM) for the characterization of materials, including some recent developments. The student should acquire the basic of elastic interaction of the electron beam with atoms and solid. They then should acquire the image formation process in a TEM and notably the case of "Phase contrast" and the case of "Amplitude contrast". From these, the students should be able to retrieve some structural parameter of nanomaterials from TEM images and diffraction such as some crystal structure or thickness. I will also detail recent developments that has lead TEM to be a unique tool for nano-characterisation and in particular some elements of correction of the aberration of electron lens. At the end, the students should also be aware of the existence of a diversity of technique available in a TEM. The course will first describe the physic of elastic interaction of an electron beam with a solid in order to induce the important key-parameters (electron wavelength, Bragg angle,) and functions (atomic scattering factors,) to understand the formation of image and diffraction. The basic elements of a transmission electron microscopy (TEM) are then described. It will be done with an emphasis on technical issues and will give the opportunity to discuss points such as resolution or signal to noise ratio. We will then describe the main principle of contrast formation in a TEM notably the phase contrast and the amplitude-diffraction contrast. We will see how high resolution atomic image can be interpreted by phase contrast and how it can be used to measure atomic distance. Examples of		

	introduced since it is the TEM technique that shows actually the faster development. This is notably due to the development of aberration correctors and some of these elements will be reported in the course. Example on how STEM can be used for characterization of devices or semiconductors will be reported. The course will be finish by the description of the spectroscopy associated to the TEM. Such spectroscopy either based on X-ray or electron are rich of information and can be used to quantify the local stoichiometry of the samples.		
課程內容 / 授課大綱 Course content / outline	The course will be divided in 6 session of 3 hours each. 1- The electron beam interacting with the materials. 2- The transmission electron microscope (TEM) 3- Image formation in a TEM. The case of weak phase object. 4- Image formation in a TEM. The case of diffraction contrast. 5- The Scanning transmission electron microscope, id est, the STEM approach. 6- Spectral characterization in a material using a transmission electron microscopy. I will first describe the electron beam interaction with materials. It includes the presentations or reminder of concept of crystal, scattering and Bragg angle, then the presentation of elastic scattering by individual atoms and crystal with and without finite size. Atomic scattering factor for electron and	授課對象 Target audience	Postgraduate

for X-ray are		
presented and discuss.		
At this point the		
student should have		
the building brick for		
understanding		
-		
diffraction and images		
(in principle whatever		
the microscope or		
involved particles).		
In a second session, I		
will give a general		
description of what a		
transmission electron		
microscope (TEM) is.		
This will be described		
in technical,		
engineering oriented		
way with a description		
of how work an		
electron gun, an		
electron round lens		
and electron detectors.		
The notion of limit of		
a TEM will be discuss		
in term of resolution		
(with respect to		
electron lens		
aberration) and of		
sensitivity or signal to		
noise ratio (depending		
on detectors).		
Examples of		
microscope,		
microscopes		
companies, range of		
price, obtained		
images, business		
applications, etc, will		
be presented and		
discussed.		
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In a third accessor and		
In a third session, we		
will describe the		
formation of phase		
contrasted images in a		
TEM. The sample is		
described as a "pure		
phase object" (it		
means that the atoms		
	<u> </u>	

of the sample only	
change the phase of	
the incoming electron,	
which actually is only	
valid for thin sample,	
but make an easy	
description). The	
microscope is then	
described as a filter in	
spatial frequencies	
and the role of	
microscope focus and	
resolution can be	
describe and discuss	
easily. It is then	
possible to discuss	
real high resolution	
TEM experimental	
images and for	
example the nature of	
contrast. 3 examples	
will be described 1)	
are the atoms the	
white or black spots in	
high resolution TEM ?	
2) how to measure the	
diameter of a	
nanotube by high	
resolution TEM, 3)	
the best choice of	
defocus for a low	
resolution biological	
U	
sample where contrast	
is more important than	
resolution.	
ar ar ar a	
In the section 4, we	
will continue to	
address the formation	
of image in a TEM.	
We will describe the	
case of image	
formation in case of	
diffraction contrasted	
where amplitude of	
the scattered beam	
play the major role.	
We will discuss the	
evolution of such	
contrast with	
thickness, orientation	
 unexitess, orientation	

or defect (dislocation)	
in the materials. This	
section will conclude	
on the general case	
-	
where Amplitude and	
Phase both play a role	
on the image	
formation.	
The section 5 will be	
devoted to the case of	
the Scanning	
transmission electron	
microscope (STEM).	
While STEM has been	
for a long time	
considered a Scanning	
module attachment to	
a TEM it is now seen	
as the most developed	
TEM techniques. I	
will discuss these	
aspect and the reason	
for (Cs corrector). I	
will then describe the	
image formation in	
STEM mode that can	
be primary discuss by	
correcting the Atomic	
scattering factor with	
a Debye Waller term.	
Example of use of	
STEM for	
characterization of	
material will be given.	
We will see how	
STEM can be used to	
measure atomic	
position of atoms or	
differentiate between	
different elements.	
Examples will	
concern devices,	
dopant, etc	
In a last section, I will	
describe how	
non-elastically	
scattered electron can	
be used to characterize	
materials. It includes	

	spectroscopy techniques related to TEM techniques. I will described two of them the EDS (X-ray spectroscopy, as emitted by the sample) and the EELS (electron energy loss spectroscopy) and their application to study material characterization.		
學習評量方式 Assessment / grading policy	(1) Report: 50%(2) Presentation: 50%		
課程目標之教學方法 Teaching methods for this course	Power point presentation and blackboard.		
教科書&参考書目 Textbook & other reference	Introduction of conventional transmission electron microscope by M. de Graef (Cambridge Univ Press). High Resolution Transmission electron microscopy and associated techniques, Editors P. Buseck, J. Cowley and L. Eyring (Oxford Press).		
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Thank you for your help!